



Strategic Product Development Announcement

29 August 2018, Sydney - Pivotal Systems Corporation ('Pivotal' or the 'Company') (ASX: PVS), a leading Silicon Valley-based, international technology company, advises that it has today entered into an unconditional Development Agreement with a leading Japanese process equipment company.

Under the agreement, Pivotal will develop a standard Gas Flow Controller for higher flows in accordance with the customer's specifications for use in the customer's products. The Gas Flow Controller developed by Pivotal under this agreement will be supplied exclusively to the customer for an agreed period following development. This new product will be focused on leading atomic layer deposition applications in the future.

The agreement is ongoing until the development of the product is completed (or terminated) and Pivotal expects this new market application to be brought to market in late 2019.

For further information, interview and photos:

Investor/Media contact (Australia):

Simon Hinsley

simon@nwrcommunications.com.au

+61401 809 653

Media Contact (US):

Rob Haralson

ANZU Partners

rh@anzupartners.com

ASX Representative:

Naomi Dolmatoff

Company Matters Pty Ltd

Naomi.Dolmatoff@companymatters.com.au

About Pivotal Systems:

Pivotal Systems Corporation (ARBN 626 346 325), is a company incorporated in Delaware, USA, whose stockholders have limited liability. Pivotal Systems provides the best-in-class gas flow monitoring and control technology platform for the global semiconductor industry. The company's proprietary hardware and software utilizes advanced machine learning to enable preventative diagnostic capability resulting in an order of magnitude increase in fab productivity and capital efficiency for existing and future technology nodes.